



# Prediction of Interconnect Pattern Density Distribution: Derivation, Validation, and Applications

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# *Outline*

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- \* Motivation

- \* Interconnect Pattern Density Model

  - \* Derivation

  - \* Validation

  - \* Applications

- \* Conclusion

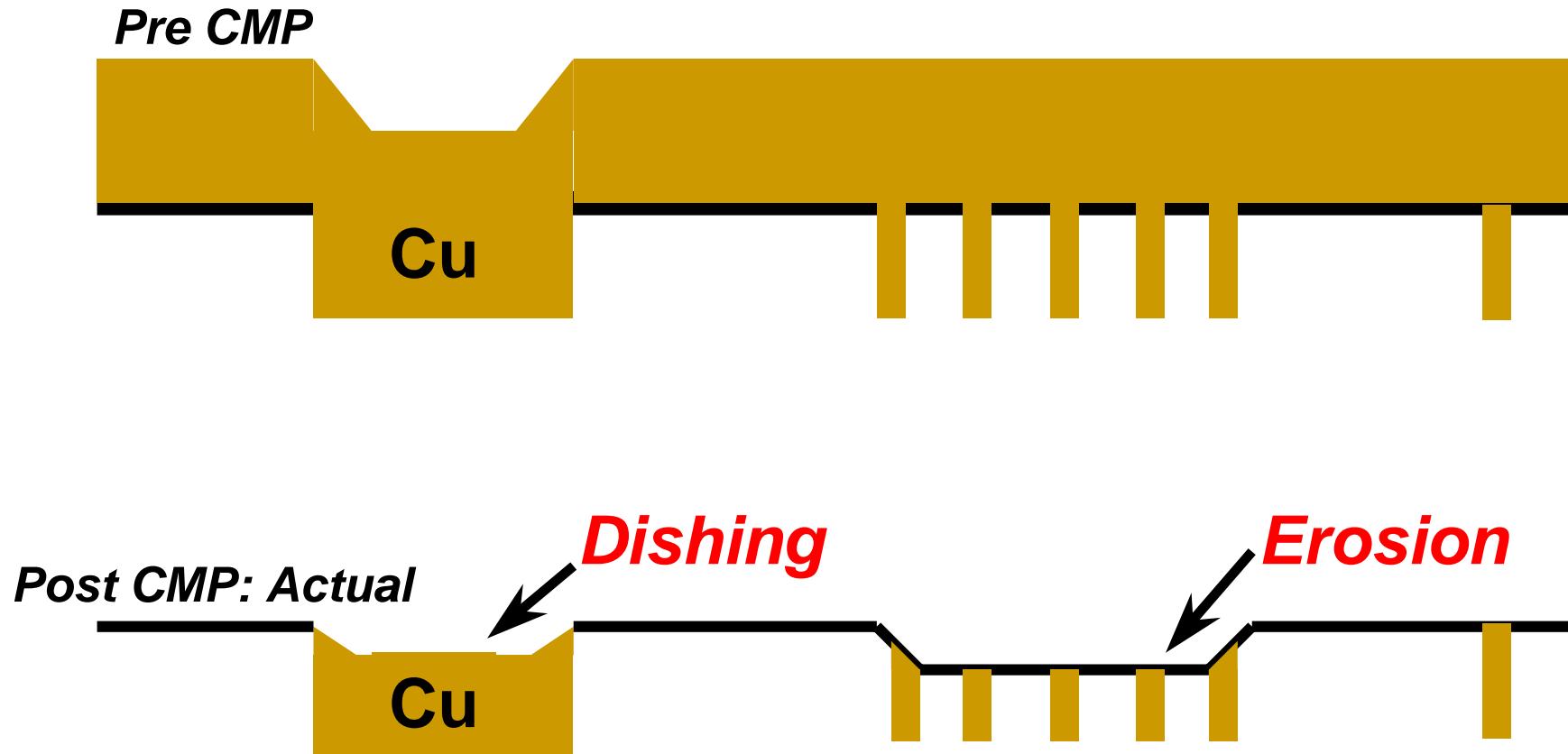
# Motivation

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- \* Large variation (+/- 30%) in metal thickness.
- \* Mostly due to effect of metal coverage (*Pattern Density*) on CMP process.
- \* Interconnect thickness variation becomes layout dependent, which makes it impossible to perform a system level analysis without a completed layout.
- \* Prediction of interconnect pattern density distribution is essential in understanding the limitations of a future technology *without* prior access to the layout details.

# *Topography After Copper CMP*

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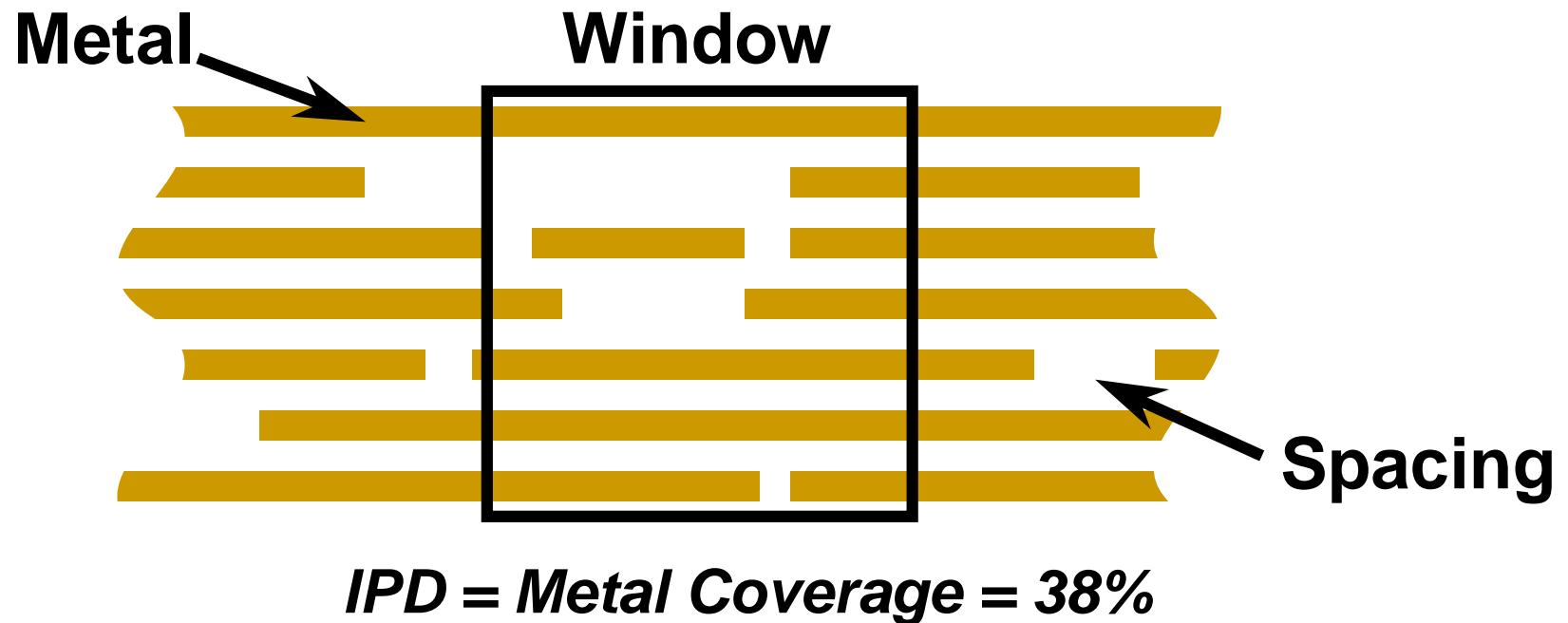
Courtesy of S. Lakshminarayanan of LSI Logic

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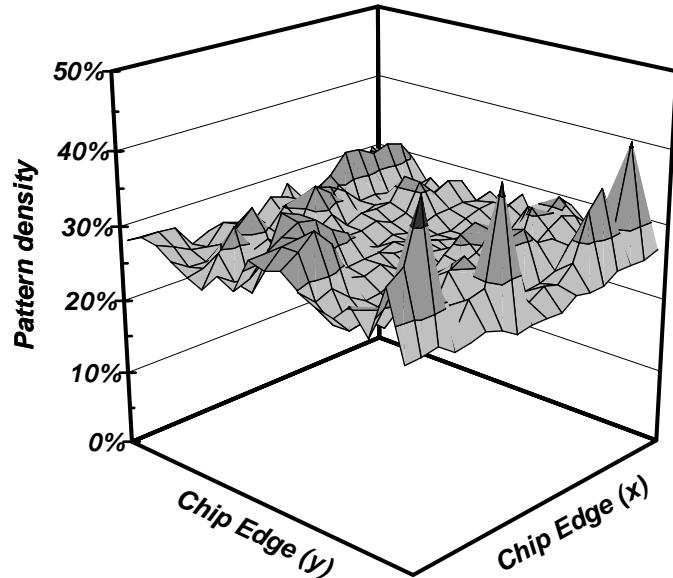
# *Pattern Density Definition*

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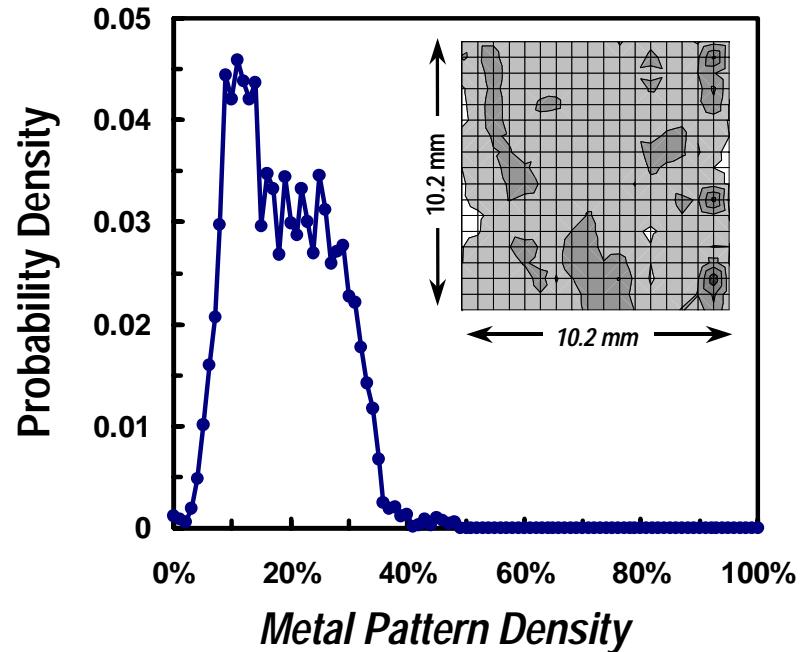
*Interconnect pattern density* (IPD) is the fractional area occupied by the metal interconnects within a window of given size.



# *IPD Probability Density Function*



A 3-D Pattern Density Distribution



Interconnect Pattern Density PDF

Design Specifications:

Metal Layer = M2  
Chip Size =  $10 \times 10 \text{ mm}^2$   
No. of Gates = 2.5 M gates

Window Size =  $100 \times 100 \mu\text{m}^2$   
Technology =  $0.18 \mu\text{m}$   
Total Metal Layers = 5

# *Outline*

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\* Motivation

\* Interconnect Pattern Density Model

\* Derivation

\* Validation

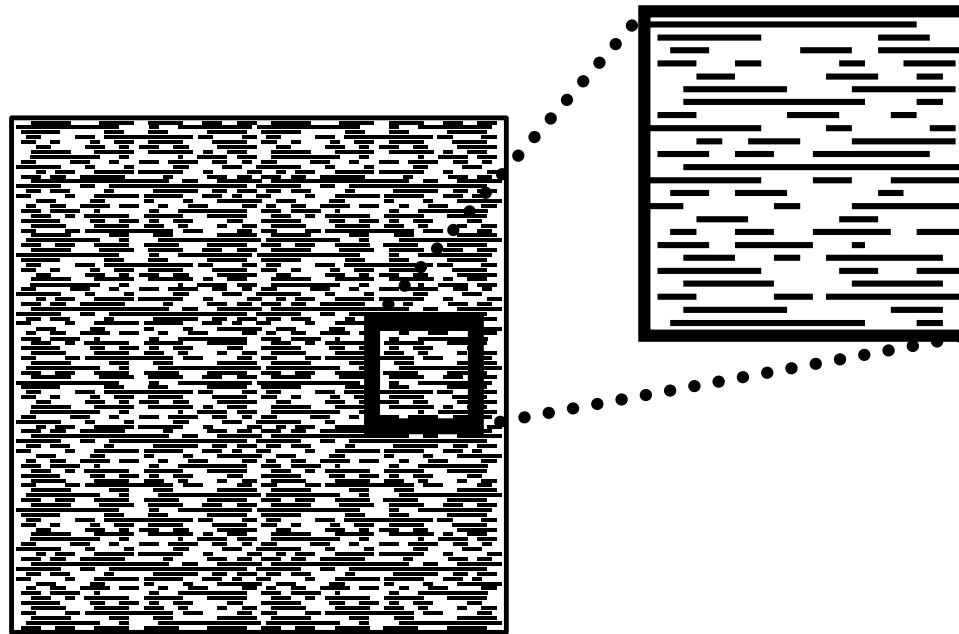
\* Applications

\* Conclusion

# *Assumption 1*

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- \* Random logic network is complex and irregular enough to be well approximated by a random variable.
- \*  $P$  = Wire placement probability (channel utilization).



# *Simple Example*

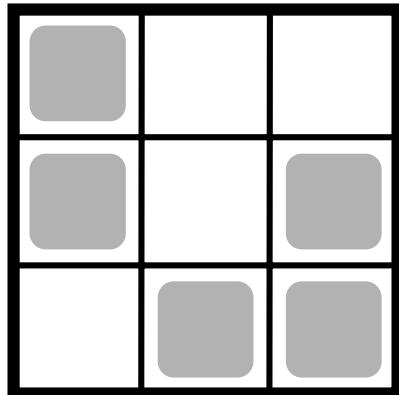
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Simplified problem:

Array size,  $n = 3 \times 3$

Probability of placing a dot,  $p = 0.75$

Probability of having 5 dots,  $f(5) = ?$



$$f(5) = \frac{9!}{5! \times 4!} (0.75)^5 (0.25)^4$$

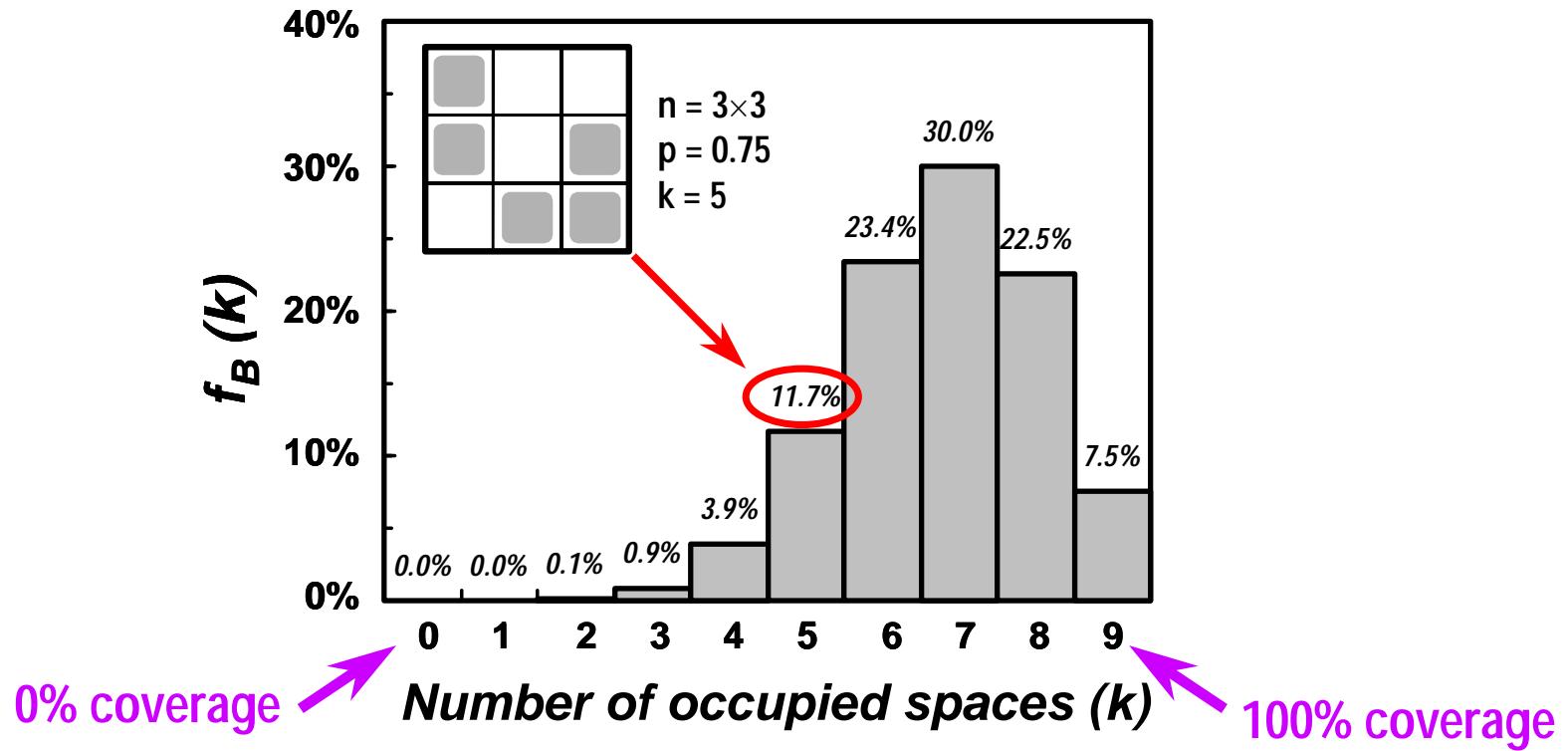
$$f(5) = 11.7\%$$



Bernoulli Probability  
Function

# *Basic IPD Distribution*

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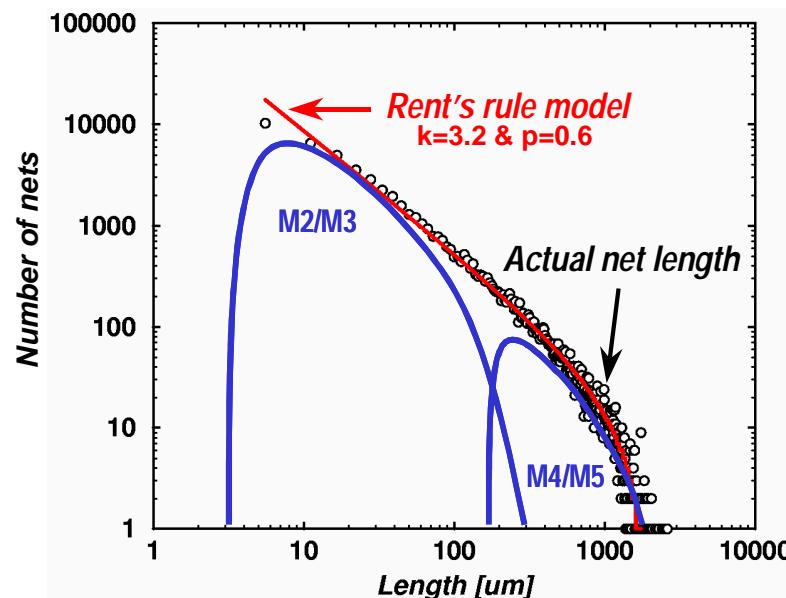
Bernoulli probability function:

$$f_B(k) = \frac{n!}{k!(n-k)!} p^k (1-p)^{n-k}$$

# Assumption 2

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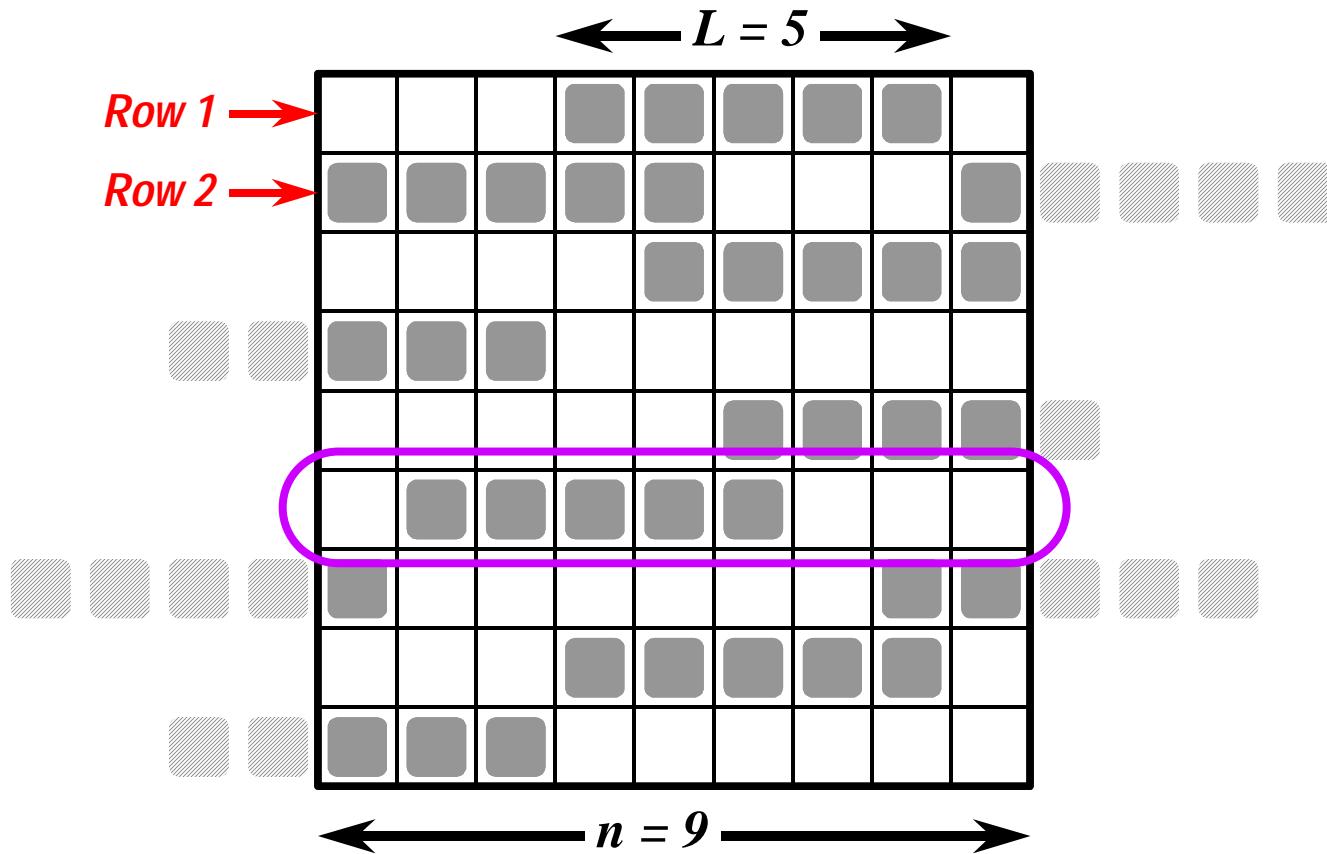
- \* We use average wire length in each metal layer.
- \* It is computed by wire allocation to that metal layer  
[P. Christie and J. Gyvez, SLIP 2001].



Courtesy of Weidan Li of LSI Logic

# *Realistic Case*

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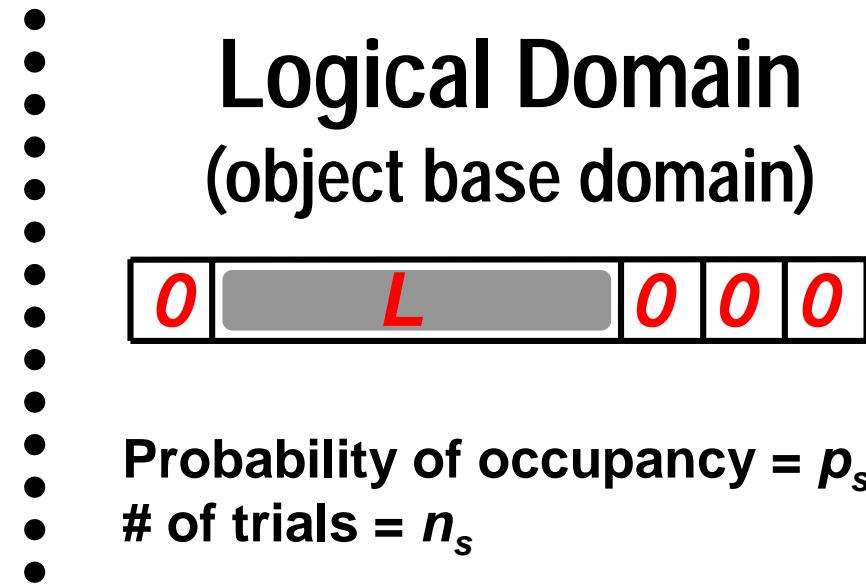


# *Physical versus Logical Domains*

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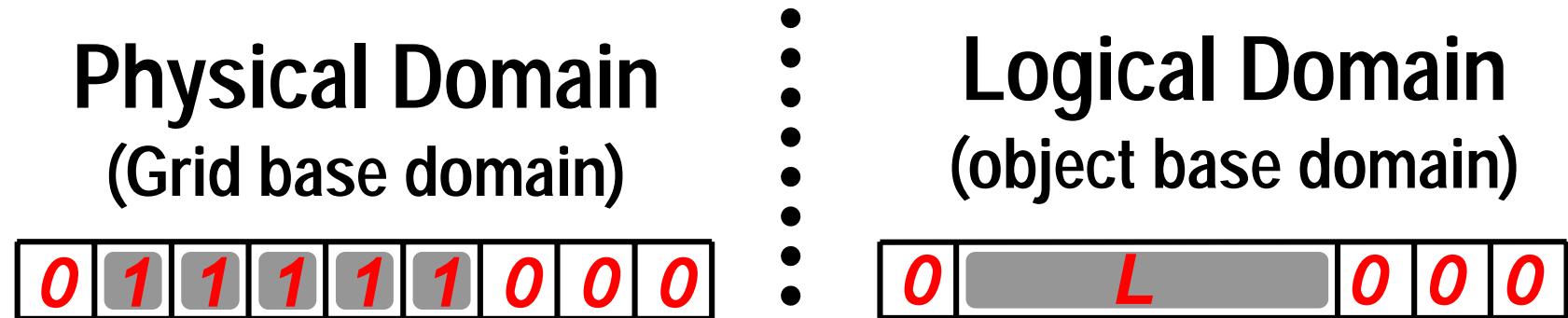
Probability of occupancy =  $p$   
# of trials =  $n$



- \* We map the problem in physical domain to logical domain to be able to use Bernoulli distribution.
- \* Then, we map the results back to the physical domain.

# *Physical versus Logical Domains*

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Probability of occupancy =  $p$   
# of trials =  $n$

Probability of occupancy =  $p_s$   
# of trials =  $n_s$

**# of filled spaces:**

$$np = L(n_s p_s)$$

**# of empty spaces:**

$$n(1-p) = n_s(1-p_s)$$

# *Physical versus Logical Domains*

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**Physical Domain**  
(Grid base domain)



Probability of occupancy =  $p$   
# of trials =  $n$

**Logical Domain**  
(object base domain)

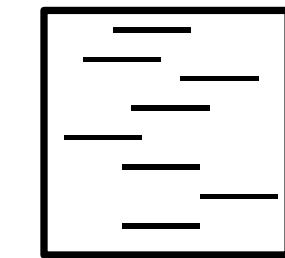


Probability of occupancy =  $p_s$   
# of trials =  $n_s$

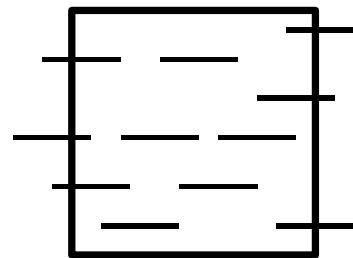
$$\frac{1}{1 + (1/p - 1)L} = p_s$$

# Interconnect Pattern Density of Row

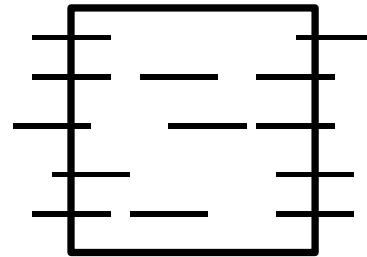
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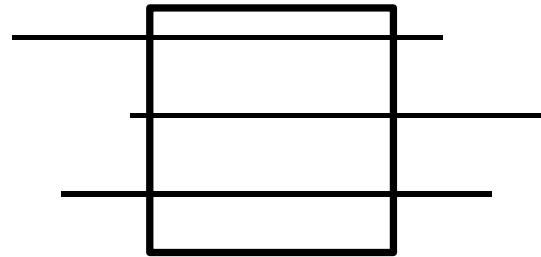
Fully inside (no crossing)  
a)  $P_0(k)$



Single side crossing  
b)  $P_1(k)$



Double side crossing  
c)  $P_2(k)$



All the way going through  
d)  $P_3(k)$

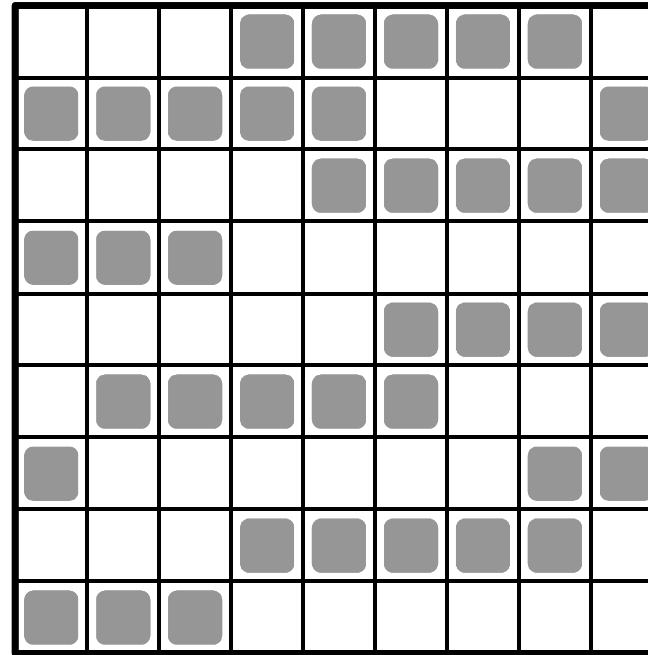
$$P_{Row}(k) = P_0(k) + P_1(k) + P_2(k) + P_3(k)$$

$$PDF_{Row}(k) = \text{norm}(P_{Row}(k))$$

# *Overall IPD distribution*

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$PDF_{Row\ 1}$  →  
 $PDF_{Row\ 2}$  →



$$IPD(k) = PDF_{Row} * PDF_{Row} * \dots * PDF_{Row}$$

# *Outline*

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\* Motivation

\* Interconnect Pattern Density Model

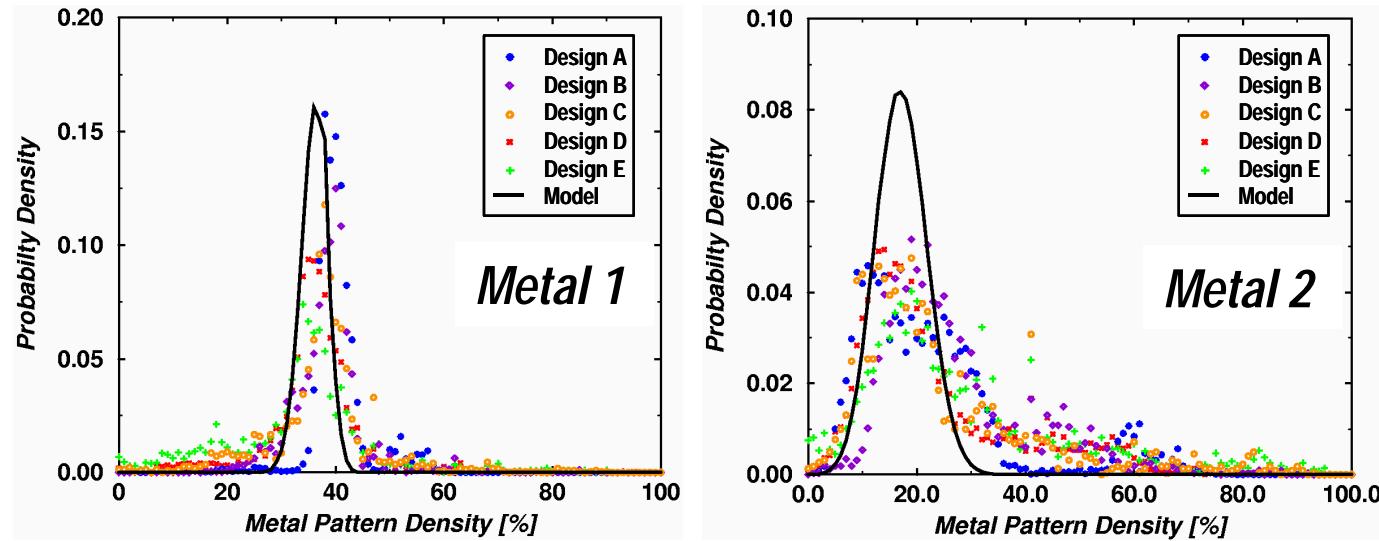
\* Derivation

\* Validation

\* Applications

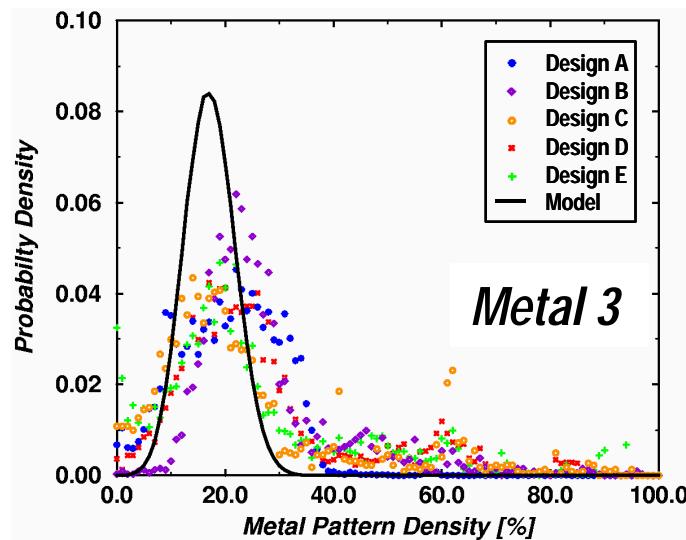
\* Conclusion

# Experimental Data



## Input Parameters

- 1) Window size
- 2) Average wire-length
- 3) Wire width and spacing
- 4) Gate pitch
- 5) Wiring utilization



# *Outline*

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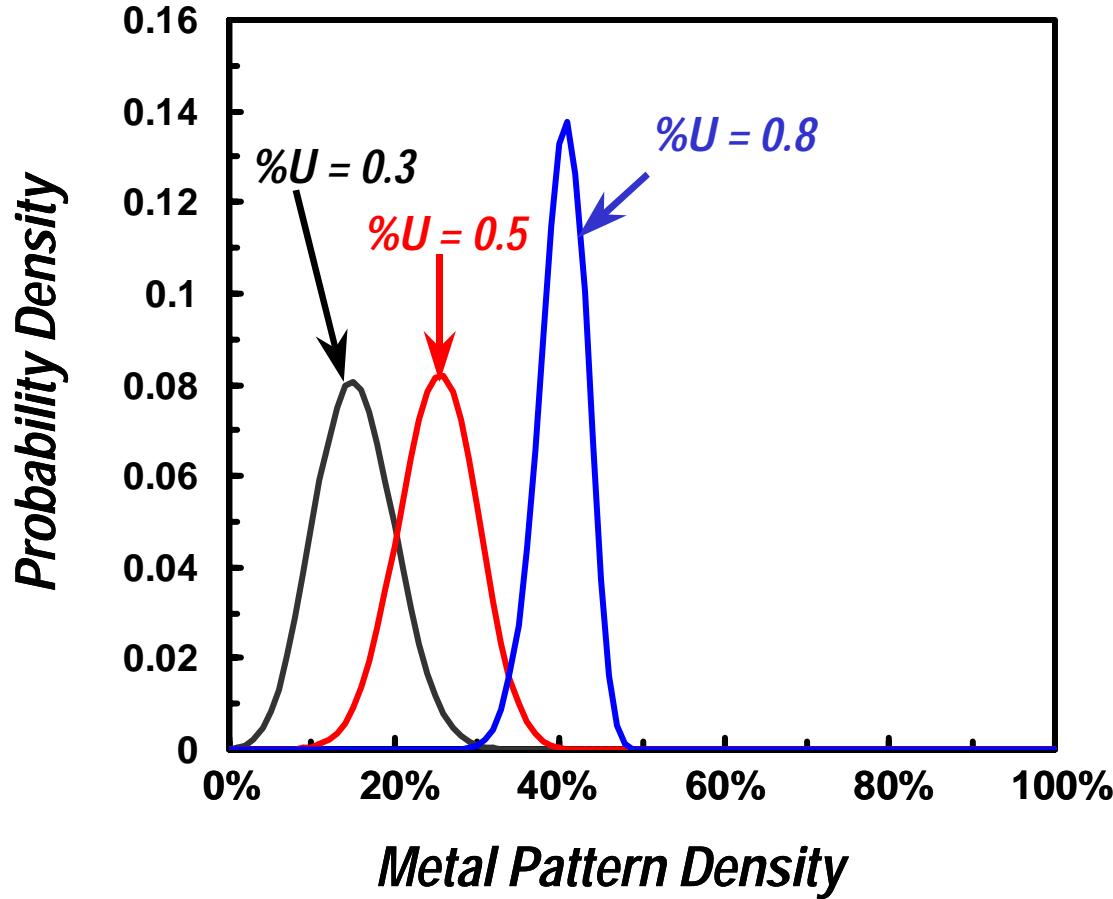
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# Application 1

*Inference of IPD Distribution*

# *Impact of Channel Utilization*

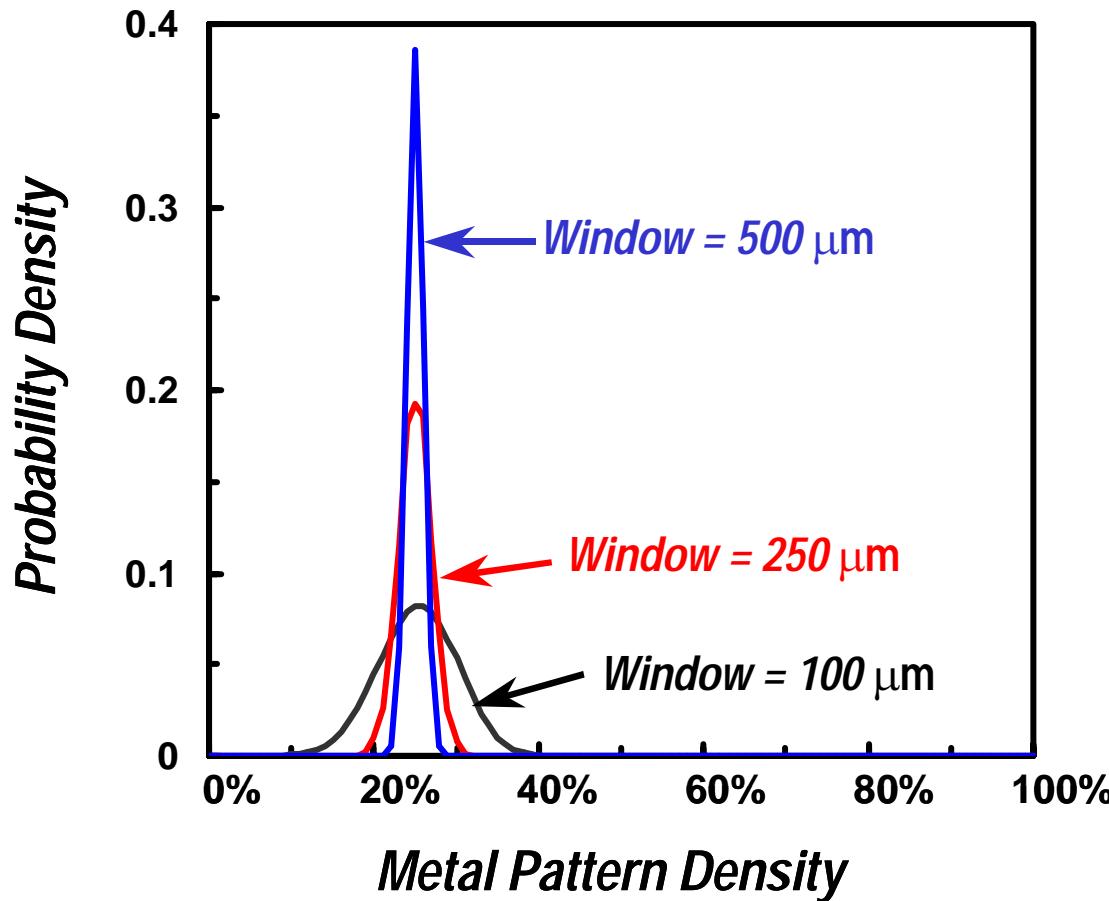
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Window = 100  $\mu\text{m}$   
length = 70  $\mu\text{m}$   
width = 0.5  $\mu\text{m}$   
spacing = 0.5  $\mu\text{m}$   
gate pitch = 10  $\mu\text{m}$

# *Impact of Window Size*

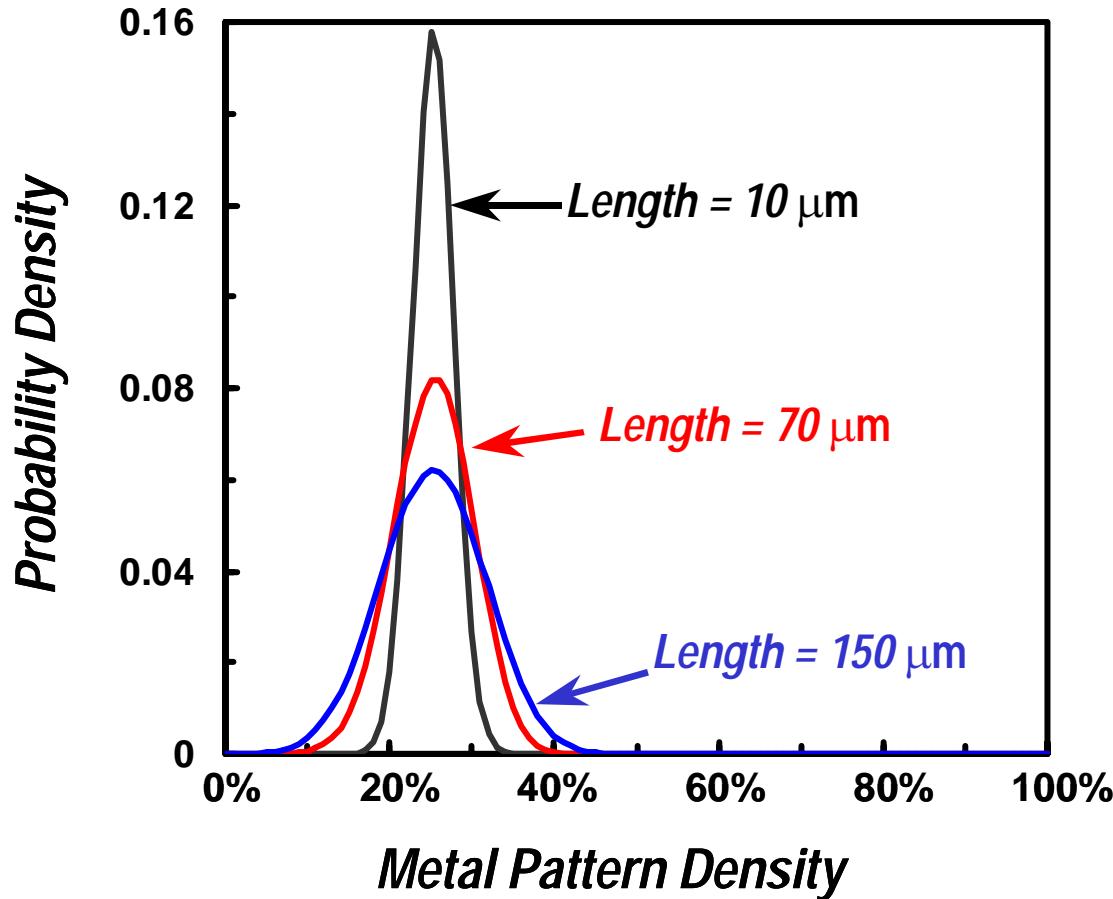
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length = 70  $\mu\text{m}$   
width = 0.5  $\mu\text{m}$   
spacing = 0.5  $\mu\text{m}$   
gate pitch = 10  $\mu\text{m}$   
utilization = 0.5

# *Impact of Wire Length*

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Window = 100  $\mu\text{m}$   
width = 0.5  $\mu\text{m}$   
spacing = 0.5  $\mu\text{m}$   
gate pitch = 10  $\mu\text{m}$   
Utilization = 0.5

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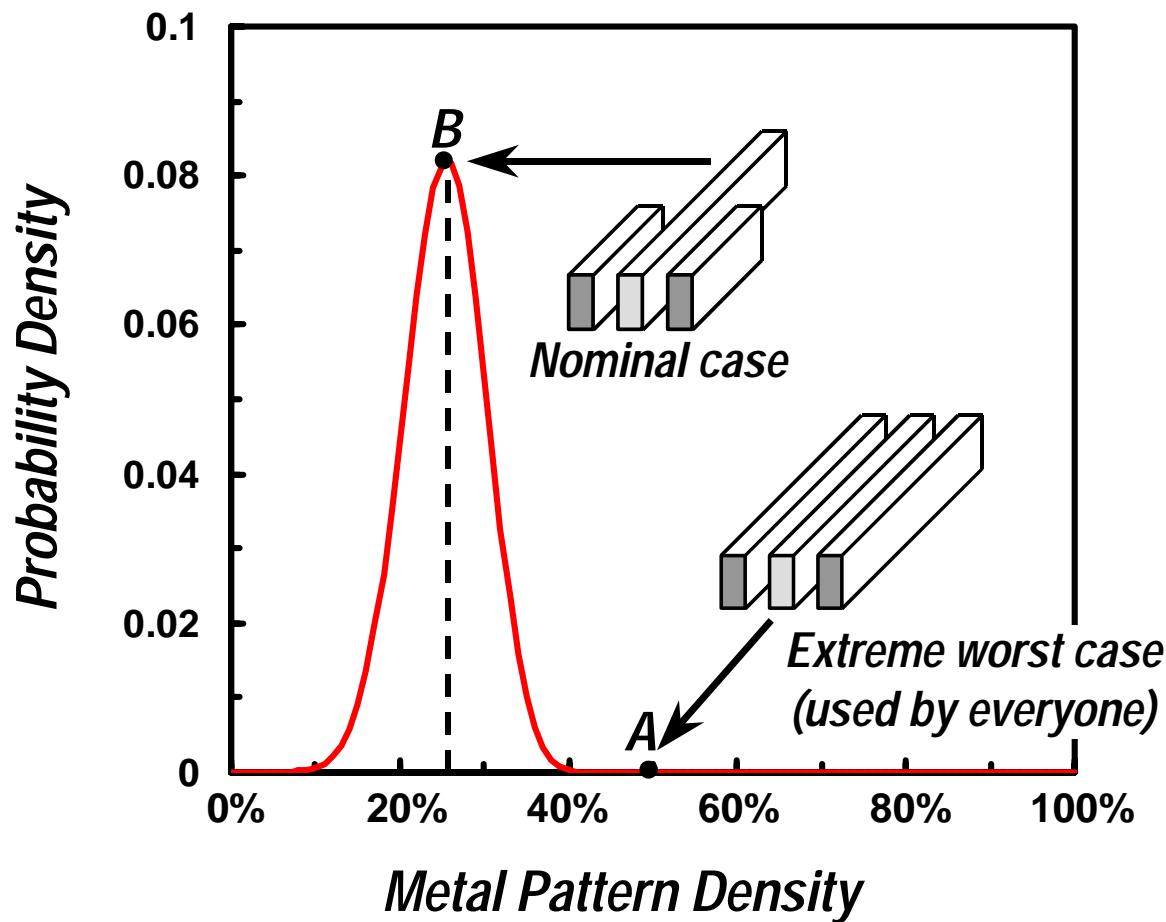
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## Application 2

*Statistical Interconnect  
Reference Circuit*

# *Statistical Interconnect Reference Circuit*

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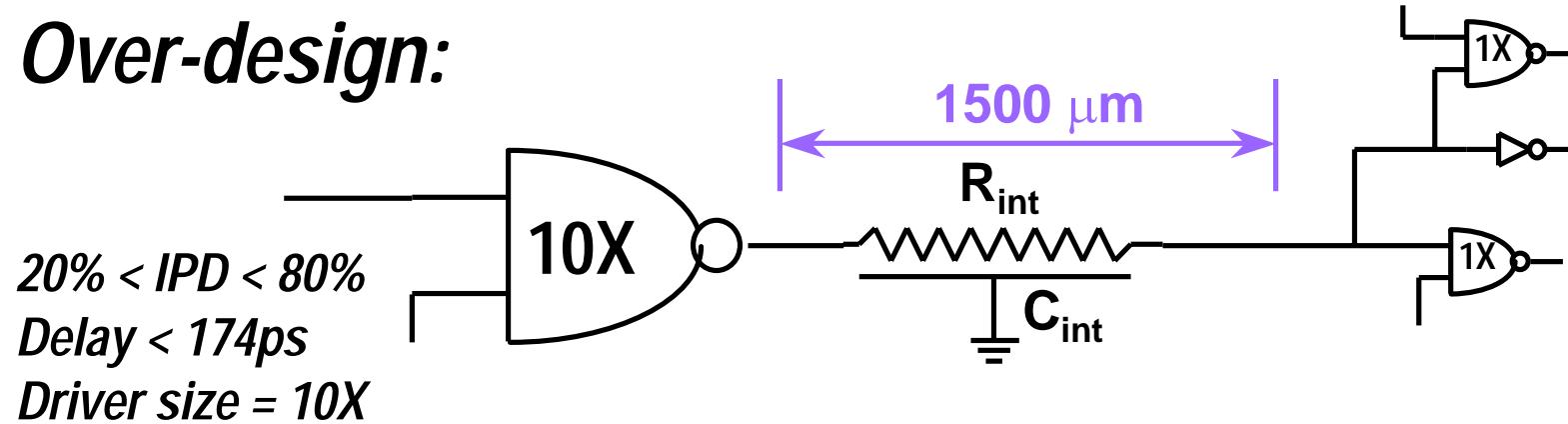
## Application 3

*Assessing the Impact of IPD  
on System Performance*

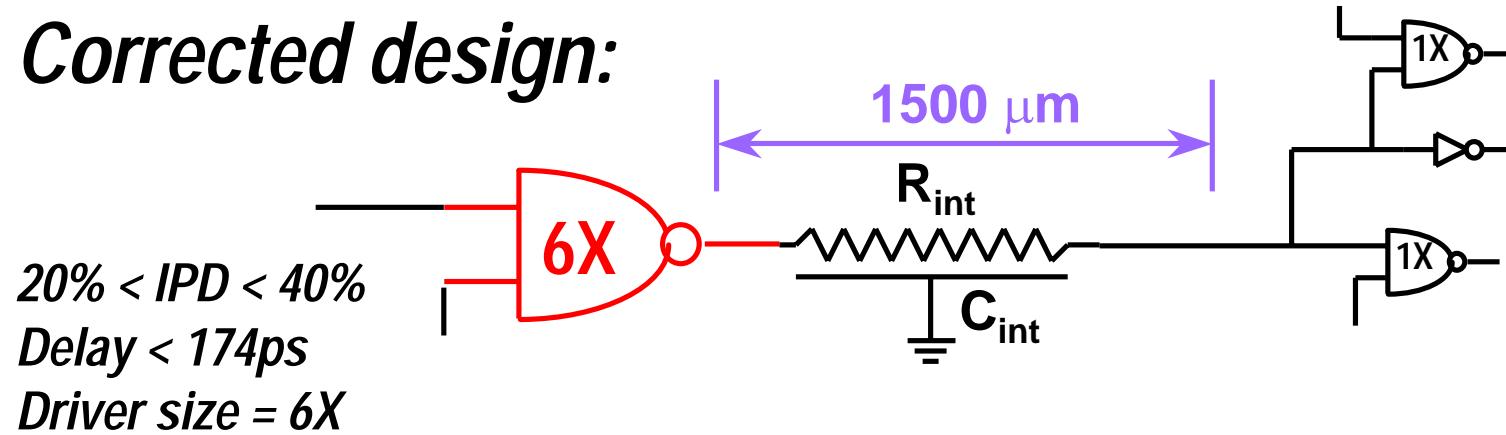
# *Circuit of a Synthetic Global Net*

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*Over-design:*

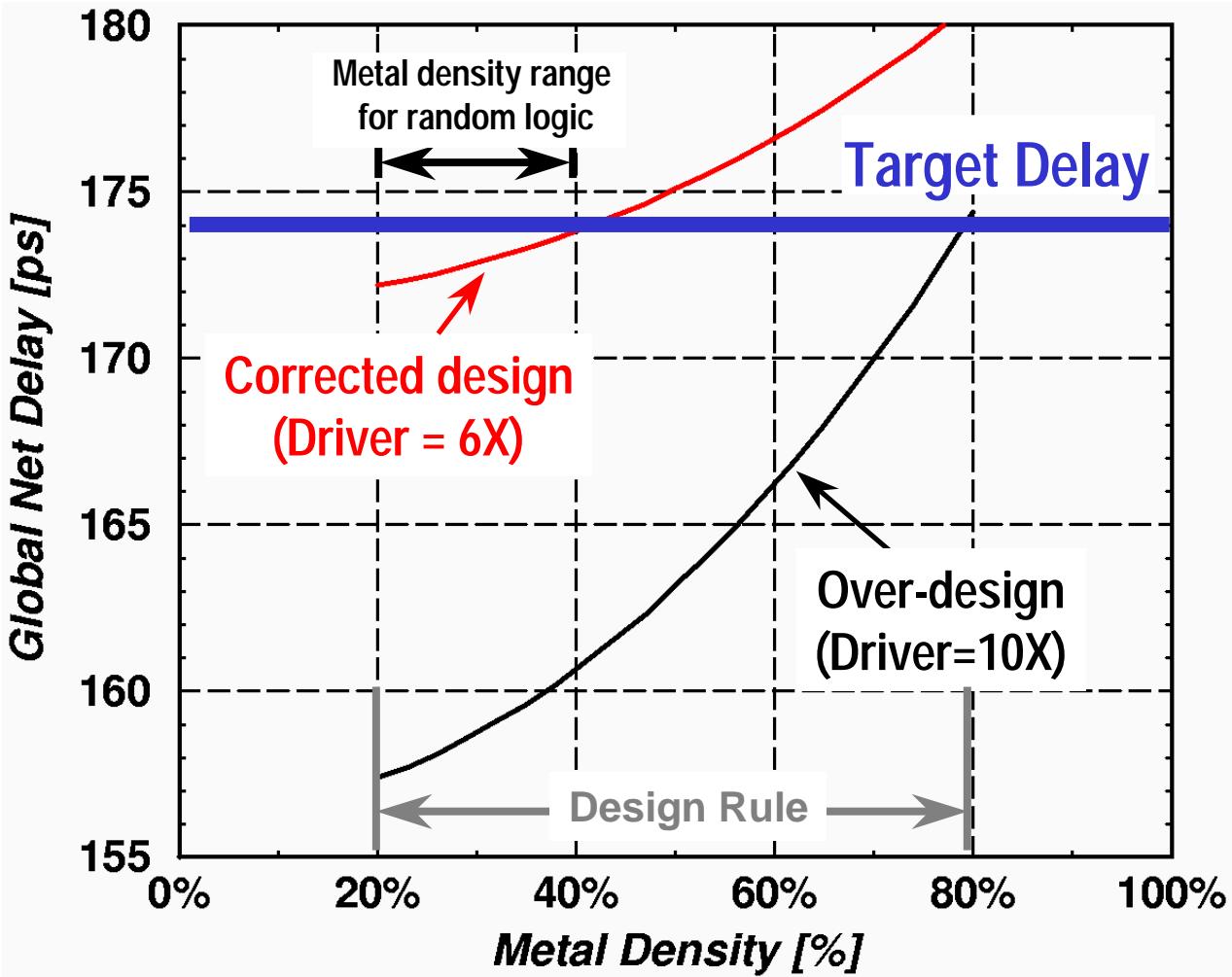


*Corrected design:*



# Wire Delay versus Metal Density

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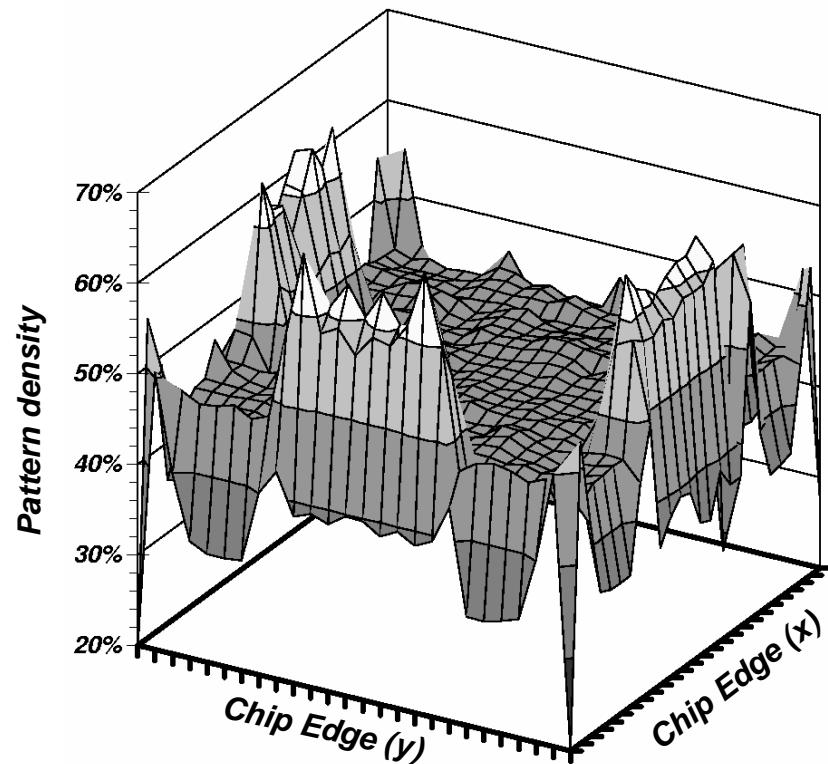
# **Conclusions**

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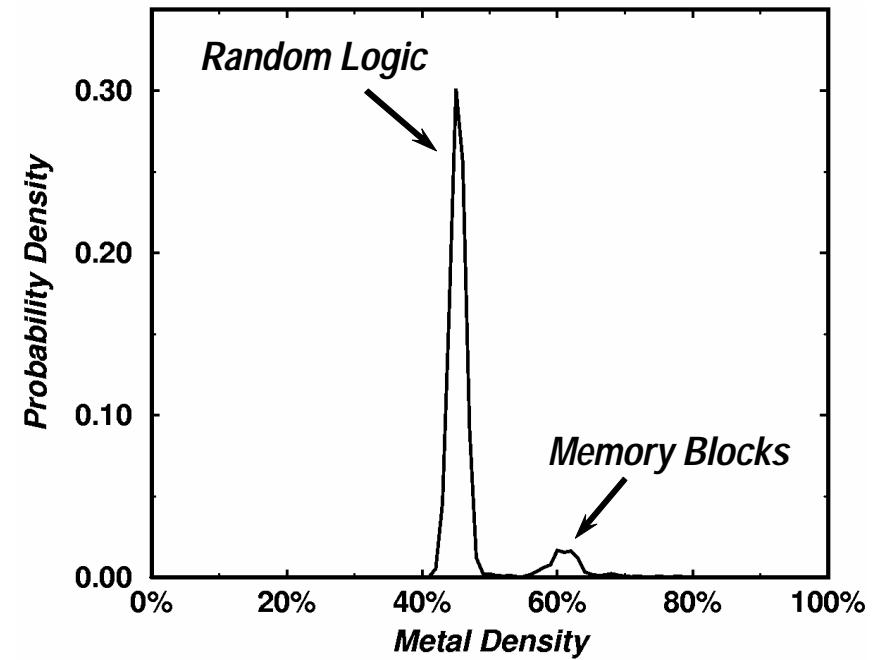
- \* Analytical model for interconnect pattern density (IPD) distribution for random logic networks is derived.
- \* The model uses only system level generic parameters such as window size, average wire-length, wire width and spacing, gate pitch, and wiring utilization.
- \* Comparison to product data confirms the accuracy of the model.
- \* Some possible applications of the IPD are proposed.

# *Impact of Memory on IPD*

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A 3-D Pattern Density Distribution



Interconnect Pattern Density PDF